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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Shafer et al.

Art Unit : Unknown

Serial No. :

Examiner : Unknown

Filed : December 21, 2005

Title : OBJECTIVES AS A MICROLITHOGRAPHY PROJECTION OBJECTIVE
WITH AT LEAST ONE LIQUID LENS

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Applicants request consideration of the references listed on the attached PTO-1449 form.

Under 37 C.F.R. § 1.98 (a)(2)(ii), only copies of foreign patent documents and/or non-patent literature are enclosed. Copies of any listed U.S. patents or U.S. patent application publications can be provided upon request. A copy of a communication from a foreign patent office in a counterpart application is also enclosed.

This statement is being filed with the application. Please apply any charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,



Sean P. Daley
Reg. No. 40,978

Date: 12/21/05
Fish & Richardson P.C.
225 Franklin Street
Boston, MA 02110
Telephone: (617) 542-5070
Facsimile: (617) 542-8906

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Substitute Form PTO-1449 (Modified)		U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 17979-034US1	Application No. 10/1562257
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Shafer et al.		
		Filing Date Herewith	Group Art Unit	

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	US2003/174408	9/18/2003	Rostalski Hans-Juergen et al.			
	AB	US2005/024609	2/3/2005	De Smit et al.			
	AC	US2005/074704	4/7/2005	Endo et al.			
	AD	US2005/0179877	8/18/2005	Mulkens et al.			
	AE	US2005/0219707	10/6/2005	Schuster et al.			

Foreign Patent Documents or Published Foreign Patent Applications							
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation
							Yes No
	AF	WO2005/006026	1/20/2005	WIPO			
	AG	WO2005/081067	9/1/2005	WIPO			
	AH	EP0291596B1	1/19/1994	EPO			
	AI	WO2005/059645	6/30/2005	WIPO			
	AJ	WO2005/059618	6/30/2005	WIPO			
	AK	WO2004/019128	3/4/2004	WIPO			
	AL	WO2005/031823	4/7/2005	WIPO			

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	AM	Hoffnagle, J.A. et al. "Liquid immersion deep-ultraviolet interferometric lithography", Journal of Vacuum Science & Technology B: Microelectronics Processing and Phenomena, American Vacuum Society, New York, NY, US, vol. 17, no. 6, November 1999 (1999-11), pages 3306-3309
	AN	Smith, et al. "Water-based 193nm immersion lithography", online, 28 January 2004, retrieved from the internet: <u>URL: http://www.sematech.org/resources/litho/meetings/immersion/20040128/presentations/06%20RIT%20microstepper%20efforts_Smith.pdf</u> , retrieved on 2005-05-24
	AO	
	AP	

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	